

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**



Application Serial No. .... 10/625,166  
Filing Date ..... July 22, 2003  
Confirmation No. ..... 8008  
Inventor ..... Janos Fucsko et al.  
Assignee..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... Stephen W. Smoot  
Attorney's Docket No. ..... MI22-2246  
Customer No. ..... 021567  
Title ..... Wet Etching Method of Removing Silicon From a Substrate

**RESPONSE TO DECEMBER 21, 2005 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**VIA U.S. EXPRESS MAIL**

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 West First Avenue, Suite 1300  
Spokane, WA 99201-3828

Responsive to the Office Action dated December 21, 2005, Applicant  
amends and remarks as follows:

**AMENDMENTS**